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## **ABSTRACT**

This invention is characterized in that, a gate electrode

27Fformed on a P-type well 3 via a gate oxide film 9, a
high-concentration N-type source layer and a highconcentration N-type drain layer 15 respectively formed apart
from the gate electrode and a low-concentration N-type source
layer and a low-concentration N-type drain layer respectively
formed so that they respectively surround the N-type source
layer and the N-type drain layer 10 and respectively parted
by a P-type body layer formed under the gate electrode 27F are
provided.